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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:		PATENT APPLICATION
Inventors:	Wei Pan, David R. Evans and Sheng Teng Hsu	
Serial No.:	Not Yet Assigned	Attorney Docket No. SLA 0499
Filed:	Herewith	
Title:	METHOD OF CONTROLLING THE INITIAL GROWTH OF CVD COPPER FILMS BY SURFACE TREATMENT OF BARRIER METALS FILMS	

Hon. Assistant Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97

Sir:

Listed on attached Form PTO-1449 is information submitted pursuant to 37 C.F.R. §1.56. A copy of each listed publication is submitted herewith.

Applicant respectfully requests that the listed information be considered by the Examiner and made of record in the above-identified application.

(Date) Oct 16, 2001

Respectfully submitted,

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